

Centura 5200 HDP Ultima+ CVD System

Product Overview

- **Product Title:** Refurbished 200 mm Centura 5200 HDP Ultima+ CVD System
- **Platform Type:** Centura 5200 HDP Ultima+
- **Wafer Size:** 200 mm
- **Historical Process Application:** FSG (configurable to customer process requirements)
- **Condition:** Refurbished / Installed configuration
- **Installation Configuration:** Through-wall installation; facilities routed through the floor
- **Service Options:** Configurable sale package, Turn-Key startup options, and Warranty available

System Architecture & Wafer Handling

- **Chamber Position A, B, & C:** HDP Ultima+ CVD Process Chambers
- **Chamber Position D:** None (Open)
- **Chamber Position E:** Multi-Slot Cooldown Chamber
- **Chamber Position F:** Standard Orienter with One-OCP Control kit (Si, Clear, and SiC capable)
- **Transfer Robot:** HP+ extended-reach robot
- **Load-Lock Type:** Narrow-body load locks with automatic tilt-out
- **Cassette Capacity:** 25-slot cassette
- **Wafer Alignment:** On-the-fly center finding and Fast wafer mapping
- **Process Slit Valves:** BKM valves at Positions A, B, and C
- **Transfer Purge:** 500 sccm N2 transfer-chamber purge MFC
- **Mainframe Nitrogen:** Regulated to 30 psi

Process Chamber Specifications (Chambers A, B, & C)

Component	Specification / Configuration
Chamber Type	HDP Ultima+ CVD
O-Rings	Chemraz / Kalrez 9100
Uniformity Option	Enhanced uniformity
Gas Distribution	24-nozzle configuration (P/N 0200-18093)
Electrostatic Chuck	HDP ESC (P/N 0040-18219)

Cathode Base	Temperature-mixed HDP CVD Ultima cathode base (P/N 0040-05887)
Turbo Pump	Ebara 1604-new
Throttle / Gate Valve	Pfeiffer pendulum valve
Remote Clean Generator	Top-mounted MKS Astron AX7670-refurbished
Wafer Temperature Monitor (WTM)	Included
Individual Heated Cathode (IHC)	10/10 standard
Coil Configuration	Balance upper coil

Pressure Measurement Instrumentation

- **0.10–100 Torr Transducer:** P/N 1350-01284; 1/4 VCR, ± 15 VDC, 15-pin D-sub
- **10 Torr Set-Point Transducer:** P/N 1350-01096; 1/4 VCR, ± 15 VDC, 15-pin D-sub
- **1000 Torr Transducer:** P/N 1350-01131; 1/4 VCR, 1%, 9-pin D-sub

Controls, Interfaces & Power

- **Controller Interface:** Seriplex controller gas-panel interface card with V452 SBC
- **Monitors:** Two flat-panel monitors
- **Communications Protocol:** SECS via RS-232
- **Controller GFCI:** 100/200 mA GFCI
- **Exhaust Type:** Top exhaust
- **Signal Tower:** Front-mounted red/amber/green 3-light tower
- **Pump Interfaces:** Provisions for load-lock, transfer, and process-chamber pumps (Chambers A, B, C)

Configurable Options

- **Gas Delivery System:** Tailored gas-panel/pallet configuration; gas species, MFC ranges, line assignments, valve types, regulators, filters, and pressure transducers customizable upon request.
- **RF Generator Package:** Selectable generator models for Chambers A, B, and C. Reference offerings include ENI, Finesse ACME, Kyosan, and Advanced Energy OPTI / Paramount (+) racks.
- **Heat Exchanger / Chiller:** Sized to match thermal load and facility requirements; hose and cable lengths customizable.